

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Wan-Thai Hsu, John R. Clark, and Clark T.-C. Nguyen

Serial No.: To be Assigned

Filed: Filed Herewith

For: Method For Making Micromechanical Structures Having At Least One Lateral
Small Gap Therebetween And Micromechanical Device Produced Thereby

Attorney Docket No.: UOM 0210 PUSP 1

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97(b)(1)**

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and § 1.97-1.98, the references listed and identified on the attached Form PTO/SB08A are being submitted herewith for consideration by the Examiner. This Statement is being filed in accordance with 37 C.F.R. § 1.97(b)(1).


While this Statement is being filed in compliance with the duty of disclosure, citation of the attached references is not to be construed as an admission that any of the references are "material" as defined under 37 C.F.R. § 1.56(b).

In accordance with 37 C.F.R. § 1.98(d), copies of the cited references are not being provided since the references were previously cited by or submitted to the Patent and Trademark Office in prior application Serial No. 09/938,411 filed August 23, 2001 (pending) of which the present application is a continuation.

Respectfully submitted,

Wan-Thai Hsu, et al.

Date: July 24, 2003

By: 
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Substitute for Form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
				Application Number	Unknown
				Filing Date	Herewith
				First Named Inventor	Wan-Thai, Hsu, et al.
				Group Art Unit	Unknown
				Examiner Name	Unknown
Sheet	1	of	2	Attorney Docket Number	UOM 0210 PUSP 1

U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No. ¹	U.S. PATENT DOCUMENT		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
		5,082,242		Bonne et al.	01-21-1992	
		5,455,547		Lin, et al.	10-03-1995	
		5,491,604		Nguyen et al.	02-13-1996	
		5,537,083		Lin, et al.	07-16-1996	
		5,589,082		Lin, et al.	12-31-1996	
		5,640,133		MacDonald et al.	06-17-1997	
		5,839,062		Nguyen et al.	11-17-1998	
		5,914,553		Adams et al.	06-22-1999	
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		6,204,737		Ella, Juha	03-20-2001	
		6,265,806		Suzuki, Kenichiro	07-24-2001	
		6,305,779		Capurso et al.	10-23-2001	
		6,316,827		Asano et al.	11-13-2001	
		6,393,913		Dyck et al.	07-28-2002	
		6,448,622	B1	Franke et al.	09-10-2002	

FOREIGN PATENT DOCUMENTS								
Examiner Initials	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ⁵ (if known)				

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

Substitute for Form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	Unknown
				Filing Date	Herewith
				First Named Inventor	Wan-Thai Hsu, et al.
				Group Art Unit	Unknown
				Examiner Name	Unknown
Sheet	2	of	2	Attorney Docket Number	UOM 0210 PUSP 1

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		HSU, WAN-THAI, ET AL., A Sub-Micron Capacitive Gap Process For Multiple-Metal-Electrode Lateral Micromechanical Resonators, Technical Digest, IEEE Int. Micro Electromechanical Systems Conf., Interlake, Switzerland, January 21-25, 2001, pp. 349-352.	
		HSU, WAN-THAI, ET AL., Mechanically Temperature-Compensated Flexural-Mode Micromechanical Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, Dec. 11-13, 2000, pp. 399-402.	
		CLARK, JOHN R., ET AL., High-Q VHF Micromechanical Contour-Mode Disk Resonators, Technical Digest, IEEE Int. Electron Devices Meeting, San Francisco, California, December 11-13, 2000, pp. 493-496.	
		CLARK, JOHN R., ET AL., Measurement Techniques For Capacitively-Transduced VHF-to-UHF Micromechanical Resonators, Digest of Technical Papers, the 11 th Int. Conf. on Solid-State Sensors & Actuators, Munich, Germany, June 10-14, 2001, pp. 1118-1121.	
		C. T.-C. NGUYEN, "Micromachining technologies for miniaturized communication devices," Proceedings of SPIE: Micromachining and Microfabrication, Sept. 20-22, 1998, pgs. 24-38	
		T. HIRANO et al., "Design, Fabrication, and Operation of Submicron Gap Comb-Drive Microactuators," Journal of Microelectromechanical Systems, March 1992, No. 1, pgs. 52-59	
		J.R. TUCKER et al., "Nanoscale FETs and STM Lithography," University of Illinois, 1995, pgs. 425-434	
		C. T.-C. Nguyen, "High-Q Micromechanical Oscillators and Filters For Communications," Int'l Symposium on Circuits and Systems, June 9-12, 1997, pgs. 2825-2828	
		K. TANAKA, "Nanotechnology towards the 21 st Century," Thin Solid Films, 1999, pgs. 120-125	

Examiner Signature		Date Considered	
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